

<b>Search Notes</b>	Application/Control No.	Applicant(s)/Patent Under Reexamination
	10667368	NOGUCHI, TAKAFUMI
	Examiner	Art Unit
	Choi, Jacob Y	2885

### SEARCHED

Class	Subclass	Date	Examiner
362	459, 545, 6, 8, 446, 470, 505, 506, 259, 231	10/20/2005	JC

### SEARCH NOTES

Search Notes	Date	Examiner
Class/Subclass & Text Search Conducted by Examiner (including class 359)	10/20/2005	JC
Updated Search Conducted by Examiner	8/29/2006	JC
Updated Search Conducted by Examiner	2/14/2007	JC
STIC Search was performed by M. Mims (e.g., diffracting grating range)	02/6/2007	JC

### INTERFERENCE SEARCH

Class	Subclass	Date	Examiner